

The following notice applies to any unclassified (including originally classified and now declassified) technical reports released to "qualified U.S. contractors" under the provisions of DoD Directive 5230.25, Withholding of Unclassified Technical Data From Public Disclosure.

NOTICE TO ACCOMPANY THE DISSEMINATION OF EXPORT-CONTROLLED TECHNICAL DATA

1. Export of information contained herein, which includes, in some circumstances, release to foreign nationals within the United States, without first obtaining approval or license from the Department of State for items controlled by the International Traffic in Arms Regulations (ITAR), or the Department of Commerce for items controlled by the Export Administration Regulations (EAR), may constitute a violation of law.
2. Under 22 U.S.C. 2778 the penalty for unlawful export of items or information controlled under the ITAR is up to ten years imprisonment, or a fine of \$1,000,000, or both. Under 50 U.S.C., Appendix 2410, the penalty for unlawful export of items or information controlled under the EAR is a fine of up to \$1,000,000, or five times the value of the exports, whichever is greater; or for an individual, imprisonment of up to 10 years, or a fine of up to \$250,000, or both.
3. In accordance with your certification that establishes you as a "qualified U.S. Contractor", unauthorized dissemination of this information is prohibited and may result in disqualification as a qualified U.S. contractor, and may be considered in determining your eligibility for future contracts with the Department of Defense.
4. The U.S. Government assumes no liability for direct patent infringement, or contributory patent infringement or misuse of technical data.
5. The U.S. Government does not warrant the adequacy, accuracy, currency, or completeness of the technical data.
6. The U.S. Government assumes no liability for loss, damage, or injury resulting from manufacture or use for any purpose of any product, article, system, or material involving reliance upon any or all technical data furnished in response to the request for technical data.
7. If the technical data furnished by the Government will be used for commercial manufacturing or other profit potential, a license for such use may be necessary. Any payments made in support of the request for data do not include or involve any license rights.
8. A copy of this notice shall be provided with any partial or complete reproduction of these data that are provided to qualified U.S. contractors.

DESTRUCTION NOTICE

For classified documents, follow the procedure in DoD 5220.22-M, National Industrial Security Program, Operating Manual, Chapter 5, Section 7, or DoD 5200.1-R, Information Security Program Regulation, Chapter 6, Section 7. For unclassified, limited documents, destroy by any method that will prevent disclosure of contents or reconstruction of the document.



DEPARTMENT OF THE NAVY
NAVAL UNDERSEA WARFARE CENTER
DIVISION NEWPORT
OFFICE OF COUNSEL
PHONE: 401 832-3653
FAX: 401 832-4432
DSN: 432-3653



Attorney Docket No. 84348
Date: 9 March 2010

The below identified patent application is available for licensing. Requests for information should be addressed to:

TECHNOLOGY PARTNERSHIP ENTERPRISE OFFICE
NAVAL UNDERSEA WARFARE CENTER
1176 HOWELL ST.
CODE 07TP, BLDG. 990
NEWPORT, RI 02841

Serial Number 12/714,629
Filing Date 1 March 2010
Inventor Derke Hughes

Address any questions concerning this matter to the Office of Technology Transfer at (401) 832-1511.

20100316207

DISTRIBUTION STATEMENT
Approved for Public Release
Distribution is unlimited

UNIFORMLY DISTRIBUTED LEAD ZIRCONATE TITANATE STRAIN SENSOR

STATEMENT OF GOVERNMENT INTEREST

[0001] The invention described herein may be manufactured and used by or for the Government of the United States of America for governmental purposes without the payment of any royalties thereon or therefore.

CROSS REFERENCE TO OTHER PATENT APPLICATIONS

[0002] None.

BACKGROUND OF THE INVENTION

(1) FIELD OF THE INVENTION

[0003] The present invention is directed to strain sensors. In particular, the present invention is directed to a uniform lead zirconate titanate sensor that locates and quantifies the strain energy from a structure.

(2) DESCRIPTION OF THE PRIOR ART

[0004] Currently, technology is being pursued that will aid the development of artificially intelligent structures or devices. These structures or devices that are considered intelligent are capable of detecting and recording parameters

associated with their environment by assessing physical properties such as temperature, pressure, humidity, seismic and mechanical vibration, and optical imaging. Once the physical parameters are detected, a given algorithm within the sensor interprets the measured parameters of the surroundings and the structure or device responds to the stimulus as programmed.

[0005] One application for the use of artificially intelligent structures is to develop boat and ship hulls with such capabilities. For example, hull array technology is the concept of producing submarines with hulls containing integrated sensors that can passively investigate the submarine's surroundings. The integrated hull array sensors detect acoustic energy found within a body of water in which the submarine is traveling. The received signals can alert the submarine to impending dangers such as torpedoes, land mines, or other submarines. Non-threatening acoustic emissions are also present in an open-sea environment generated by marine life. The interpretation of the measured signals by the sensors allows the vessel to listen to its surroundings in multiple directions and distinguish between various acoustic emissions.

[0006] To accomplish integrated hull array technology, what is needed is a uniform lead zirconate titanate sensor that locates and quantifies the strain energy from a structure, and is capable of being embedded into a composite material. A

standard lead zirconate titanate sensor has a directional dependence on the strain measurement as a result of the rectangular shape of the lead zirconate titanate wafer portion of the sensor. What is needed is a uniform lead zirconate titanate sensor that is not directionally dependent, because the lead zirconate titanate wafer has a constant radius. The constant radius creates a uniform strain despite the direction of the wave front contact point on the lead zirconate titanate sensor. Therefore a uniform lead zirconate titanate wafer unlike a rectangular one registers the same voltage reading regardless of the path of the strain wave.

SUMMARY OF THE INVENTION

[0007] It is a general purpose and object of the present invention to present a design for a uniform lead zirconate titanate sensor that is not directionally dependant because it has a constant radius.

[0008] The above object is accomplished with the present invention through the use of a strain sensor that locates and quantifies the strain energy from a structure. The strain sensor has a lead zirconate titanate wafer with a circular shape such that the shape does not directionally restrict the signal of the sensor.

BRIEF DESCRIPTION OF THE DRAWINGS

[0009] A more complete understanding of the invention and many of the attendant advantages thereto will be more readily appreciated by referring to the following detailed description when considered in conjunction with the accompanying drawings, wherein like reference numerals refer to like parts and wherein:

[0010] FIG. 1a shows a prior art standard lead zirconate titanate strain sensor;

[0011] FIG. 1b shows a uniform lead zirconate titanate strain sensor of the present invention;

[0012] FIG. 2 illustrates an aspect ratio inherent in rectangular sensors; and

[0013] FIG. 3 depicts averaging higher order strain waves.

DETAILED DESCRIPTION OF THE INVENTION

[0014] A standard prior art strain sensor 10 such as the one illustrated in FIG. 1a operates in the following manner: a piezo-electric material deflects a wave front and creates a voltage difference between the top and bottom portion of the piezo-electric wafer. In a preferred embodiment, the piezo-electric material is a composite wafer 12 of lead zirconate and titanate. The lead zirconate titanate wafer is rectangular in shape. Disposed over the surface of the lead zirconate titanate wafer are wire traces 14 capable of carrying an electric

current. The wire traces carry the voltage out of the lead zirconate titanate wafer and into a pin connector 16 joined to the end of the wafer. The lead zirconate titanate wafer 12 and wire traces 14 are covered with polyimide film 18 that serves as an overall protective layer to prevent corrosion and contamination. The voltage generated by the sensor 10 can be measured by any standard data acquisition system.

[0015] The strain sensor design of the present invention 20 is one with a circular piezo-electric wafer 22 portion having a constant radius thereby making it uniform. In a preferred embodiment, the piezo-electric wafer 22 is a composite of lead zirconate and titanate. Disposed over the surface of the lead zirconate titanate wafer are wire traces 14 capable of carrying an electric current. The wire traces carry the voltage out of the lead zirconate titanate wafer and into a pin connector 16 joined to the end of the wafer. The lead zirconate titanate wafer 22 and wire traces 14 are covered with polyimide film 18 that serves as an overall protective layer to prevent corrosion and contamination. The voltage generated by the sensor 20 can be measured by any standard data acquisition system. The circular shape of the piezo-electric wafer 22 does not directionally restrict a signal of the sensor 20. The constant radius creates a uniform strain despite the direction of the wave front contact point on the lead zirconate titanate sensor

20. Therefore a uniform lead zirconate titanate wafer 22 unlike a prior art rectangular one 12 registers the same voltage reading regardless of the path of the strain wave.

[0016] Referring to FIG. 2, there is illustrated several features of the uniform distributed lead zirconate titanate strain sensor 20 that are new and innovative. These features attest to the advantages of the design. For example, the standard prior art strain sensor 10 that is directionally dependent generates a signal that is more difficult to process due to the direction of the wave front 24 contact. The point of contact 26 can create errors in both time of arrival and amplitude, because the leading edge of the signal is critical in deducing these parameters. The uniform distributed lead zirconate titanate strain sensor 20 of the present invention does not directionally restrict the signal. Rather than having varying strain at the various contact points 26 with wave fronts 24 that a standard rectangular strain sensor 10 has due to its inherent aspect ratio, the errors associated with a uniform strain sensor 20 are constant due to its constant radius.

[0017] Referring to FIG. 3 there is illustrated a lead zirconate titanate wafer 28 with wave fronts 24 impinging on the surface and the strain wave energy 30 generated by the wave fronts. The higher frequency signals are more susceptible to

averaging out the strain wave energy experienced by the lead zirconate titanate wafer.

[0018] The advantage of the present invention is that it will retain the structural ruggedness, thermal properties and thin design of prior art lead zirconate titanate sensors while not being directionally dependant because it has a constant radius.

[0019] While it is apparent that the illustrative embodiments of the invention disclosed herein fulfill the objectives of the present invention, it is appreciated that numerous modifications and other embodiments may be devised by those skilled in the art. Additionally, feature(s) and/or element(s) from any embodiment may be used singly or in combination with other embodiment(s). Therefore, it will be understood that the appended claims are intended to cover all such modifications and embodiments, which would come within the spirit and scope of the present invention.

UNIFORMLY DISTRIBUTED LEAD ZIRCONATE TITANATE STRAIN SENSOR

ABSTRACT

The invention as disclosed is a strain sensor that locates and quantifies the strain energy from a structure. The strain sensor has a lead zirconate titanate wafer with a circular shape such that the shape does not directionally restrict the signal of the sensor.

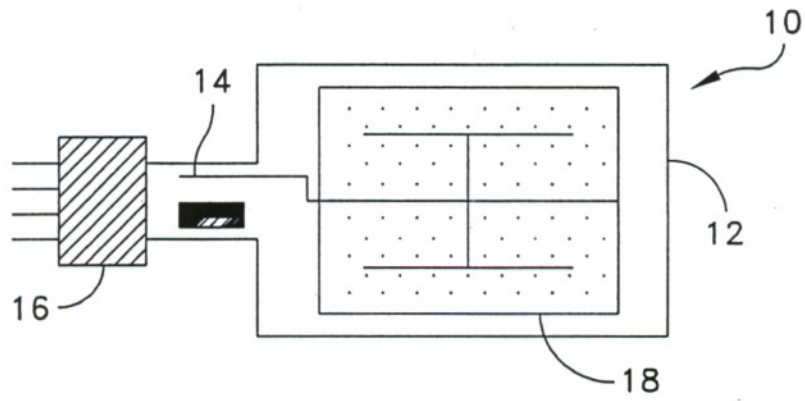


FIG. 1a
(PRIOR ART)

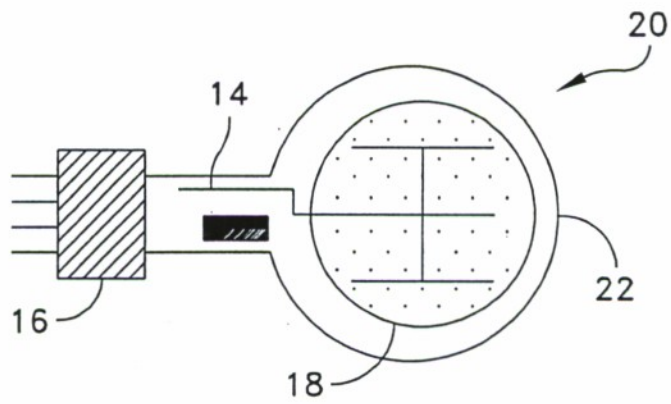


FIG. 1b

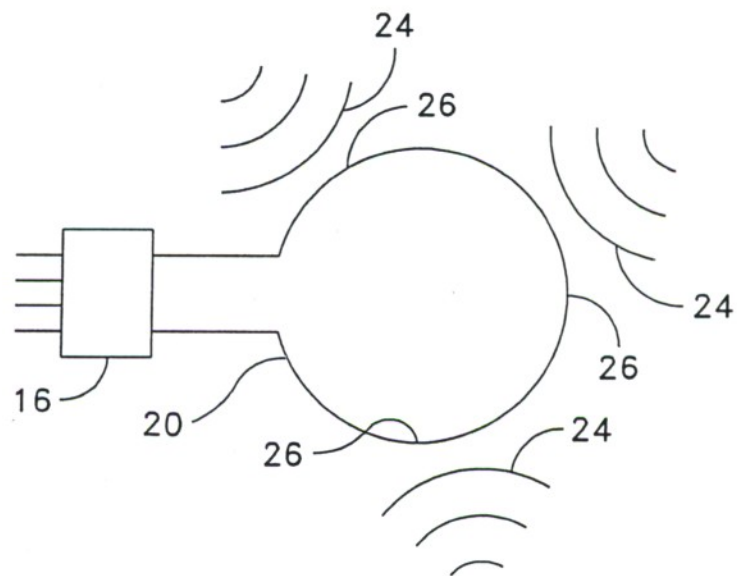
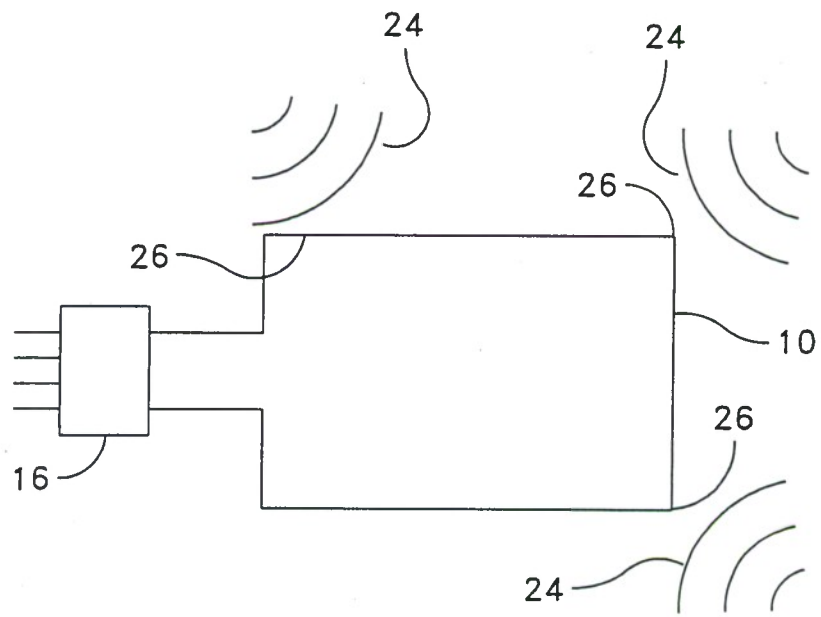


FIG. 2

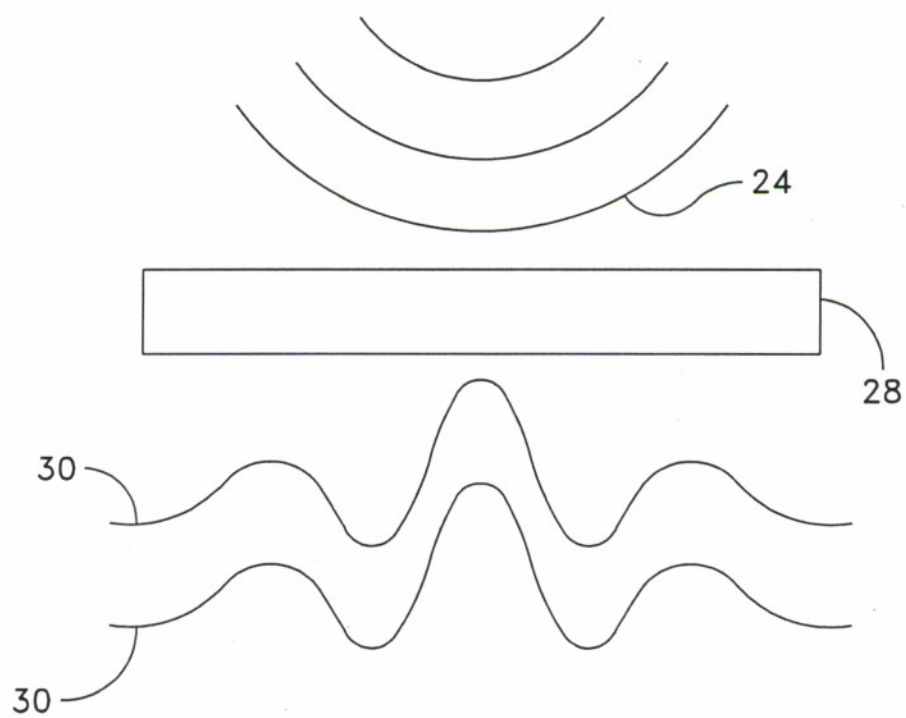


FIG. 3